### Characterization of the SiPMs of the TOF-WALL Detector

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#### Analysis workflow for SiPM characterization

# Single signal: DLED technique

DLED technique is a filtering procedure with the aim to reduce single cell pulse width.

- An original waveform replica delayed by 5 ns is created;
- This delayed replica is subtracted to original waveform.



### Single signal: waveform correction

In this correction procedure, single cell signals well separated in time are selected and averaged to create a new DLED waveform  $\rightarrow$  undershoot corrected.



## Gain

• For each bias

voltage value, areas histogram was built;

 distance between the two peaks A<sub>c</sub> is the area corresponding to a single cell. It was used to estimate the SiPM gain:

$$G = rac{A_c}{e \cdot T}$$

where  $e = 1.67 \cdot 10^{-19} C$ is the elementary charge and T = 2373 V/A is the transimpedence.



## Gain vs voltage

In order to estimate V of breakdown, all gain values with respective voltage values was fitted with a linear function y(V) = a + bV. Using fit results:  $V_{br} = -\frac{a}{b} = 106.3 \pm 0.2 V$ 



## Analysis of DLED signal



# Cross-talk probability

• Once the amplitudes histogram was built, peaks corresponding to one and two triggered cells respectively were identified;

by

finding the middle point between two first peaks, one-cell events  $n_1$  are recognized;

cross-talk

probability is estimated by the formula:

$$P_{CT} = \frac{n_{tot} - n_1}{n_{tot}}$$

where  $n_{tot}$  is the number of all the events.



# After-pulse probability

- The histogram of all time distances between two consecutive peaks was built;
- since primary dark events follow a Poisson distribution, the histogram was fitted with a decreasing exponential function;
- events n<sub>af</sub> that exceed the fit line are related to after-pulse;
- after-pulse

probability is obtained by the formula:

$$P_{AF} = rac{n_{af}}{n_{tot}}$$



## Cross-talk and after-pulse probability vs voltage



#### Light attenuation and time resolution of TOF-Wall bar

#### Experimental setup

- Bias voltage of SiPM was set to 120 V.
- Each distance measurement was evaluated from the right side of the bar.
- Source was moved from the right side to the left side with step of 1 cm.



#### SiPM waveforms at distance d = 10 cm



### Waveforms area

- After subtracting the baseline, signals area was calculated.
- $\bullet\,$  For a fixed value of distance, a  $\beta$  spectrum-like distribution is expected.
- $\bullet$  No analytical expression  $\rightarrow$  could not be fitted.



## Left-right charge ratio

• For a fixed distance d, the output signals depend on many effects:

- source spectrum is continuous;
- light emission spectrum of scintillator is continuous.
- To avoid all these variables, the ratio of left and right SiPM charge was considered.
- Scintillation light follows a decreasing exponential law:  $I(x) = I_0 \ e^{-\frac{x}{\lambda}}$
- For a fixed x coordinate on the bar:

$$I_R(x) = I_0 \ e^{-\frac{x}{\lambda}}; \quad I_L(x) = I_0 \ e^{-\frac{I-x}{\lambda}}$$

where I = 44 cm total lenght of the bar.

# Left-right charge ratio

For each side:

- charge histograms were built;
- left-right ratio was calculated;
- respective histrograms were built and fitted with a Gaussian function.



## Left-right signal ratio: results

• Mean points of the Gaussian distributions and respective distance values *d* were fitted with the function:

$$f(d) = C \ e^{-\frac{l-2d}{\lambda}}$$

- where C takes into account of gain differences between the two SiPM.
- Results:
  - $C = 0.79 \pm 0.01$
  - $\lambda = (28.4 \pm 0.2)$  cm



## Time resolution: CFD technique

For each distance value:

- the baseline of the signal was subtracted;
- a fraction (0.3) of maximum of the waveform  $V_{th}$  was chosen;
- $t_L$  and  $t_R$  were set as the time when left and right waveforms crossed  $V_{th}$ .



## Time resolution: CFD technique

For each distance value:

- time CFD was calculated as  $t_{CFD} = t_R t_L$ ;
- $t_{CFD}$  distributions were fitted with a Gaussian to estimate  $\mu_t$  and  $\sigma_t$ .



#### Time resolution: results

 $\mu_t$  values as a function of distance were fitted with a linear function  $\mu_t(d) = m \ d + q$  that provided: •  $m = (1.355 \pm 0.004) \ 10^{-10} \text{ s cm}^{-1}$ •  $q = (-4.8 \pm 0.1) \ 10^{-10} \text{ s}$ 



#### Saturation of TOF-Wall SiPMs

#### Experimental setup

- A single  $3 \times 3 \text{ mm}^2$  SiPM with 25  $\mu m$  cells size (MPPC, Hamamatsu Photonics);
- A TOF-Wall SiPM (series of 4 single SiPMs);
- A laser (PDL 800-B),  $\lambda =$  405 nm, with a light diffuser;
- A calibrated photodiode (FDS1010, Thorlabs);
- A function generator used as external trigger for the laser.



## Data taking: SiPM signals

- An overvoltage of 4 V was reached by applying a bias voltage of 56 V to the single SiPM and of 120 V to the TOF-Wall SiPM.
- A pulse frequency  $\nu_{LASER} = 1.07$  MHz was set as laser external trigger.
- By changing the laser intensity, about 15000 waveforms were acquired and respective photocurrent and dark current were measured.



## Data analysis

For each laser intensity value:

- charge histograms were built and fitted with a Gaussian function;
- effective photodiode current was estimated by subtracting dark current from photocurrent.



### Data analysis

Once all charges Q and current I values were collected:

• the number of fired cells was calculated with the formula:

$$N_{fired} = rac{A}{e \ R \ G}$$

• the number of detected photons was calculated with the formula:

$$N_{ph} = f rac{I}{
u_{LASER} E_{ph} \eta(\lambda)}$$

where: A signals area obtained by the Gaussian fit,  $R = 50 \Omega$  resistance of the oscilloscope,  $e = 1.6 \ 10^{-19} C$  elementary charge, G SiPM gain,  $E_{ph} = 4.9 \ 10^{-19} J$  photons energy and f ratio between SiPM surface and photodiode surface.

### Saturation model

All data were fitted with the saturation formula:  $N_{fired} = N_{tot} \left(1 - e^{-kN_{ph}}\right)$ 

- Single SiPM:  $N_{tot} = 5036 \pm 44$ ,  $k = (3.42 \pm 0.08) \ 10^{-5}$ ,  $\chi^2_{red} = 1.1$
- TOF-Wall SiPM:  $N_{tot} = 19115 \pm 140$ ,  $k = (1.08 \pm 0.03) \ 10^{-5}$ ,  $\chi^2_{red} = 1.2$
- The results have not been yet corrected for the voltage drop on the filter resistor.



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#### Conclusions

- The most relevant parameters of the SiPMs have been studied. These parameters can be used to reproduce the SiPM response in simulation.
- The light attenuation along the bar has been studied using an electron source. The results are not consistent with the one obtained at CNAO since a higher attenuation length is obtained in this case.
- The SiPM saturation is currently under investigation to understand the relevance of this contribution when heavy ions were used.